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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Yasunaga KAYAMA et al.

Application No.: 10/582,488

Filed: June 12, 2006

Docket No.: 127629

For: PROJECTION EXPOSURE APPARATUS AND STAGE UNIT, AND EXPOSURE METHOD

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

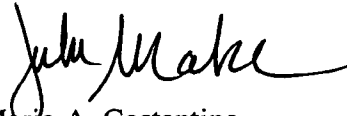
- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. Relevance of one or more non-English language reference is discussed in the present specification. See References 136-140 and 171.
- ☒ 3. One or more reference cited herein was cited in a counterpart foreign application. An English language version of the foreign search report is attached for the Examiner's information. See References 130, 132, 134 and 171.
- ☒ 4. In accordance with 37 CFR §1.98(a)(2)(ii), copies of any U.S. patents and patent application publications are not attached.
- ☒ 5. An English language Abstract of one or more non-English language reference is attached hereto. See References 121-140 and 169.

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /M.A./

☒ 6. A computer-generated English language translation of one or more Japanese Patent Publication cited herein has been obtained from the website of the Japanese Patent Office ([<http://www.jpo.go.jp>]), and is attached, but has not been reviewed for accuracy. See References 136-137 and 139-140.

☒ References 211-214 correspond to references 136-139 respectively.

Respectfully submitted,



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Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 127629	APPLICATION NO. 10/582,488
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	207	Owa, Soichi, et al., "Immersion Lithography; Its Potential Performance and Issues," Optical Microlithography XVI, Proceedings of SPIE, Vol. 5040, pp. 724 - 733 (Anthony Yened., 2003).					
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EXAMINER /Mestlin Asfaw/				DATE CONSIDERED 07/31/2008			
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Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 127629		APPLICATION NO. 10/582,488	
INFORMATION DISCLOSURE STATEMENT  (Use several sheets if necessary)				APPLICANT(S) Yasunaga KAYAMA et al.			
				FILING DATE June 12, 2006			
U.S. PATENT DOCUMENTS							
Examiner Initials	Cite No.	Document Number	Date	Name			
	211	2003/0025890 A1	02/06/2003	Nishinaga			
	212	5,448,332	09/05/1995	Sakakibara et al.			
	213	4,780,617	10/25/1988	Umatate et al.			
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FOREIGN PATENT DOCUMENTS							
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation	
OTHER DOCUMENTS							
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)					
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